

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)					Docket No. AMAT/5192		Serial No. 09/776,329	
LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT (Use several sheets if necessary)					Applicant Seutter, et al.		Confirmation No. 9575	
Examiner Unknown					Filing Date February 02, 2001		Group 2812 22	

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*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate	
TMT	A1	4,058,430	11/15/77	Suntola et al.	156	611	11/25/1975	
	A2	4,389,973	06/28/83	Suntola et al.	118	725	12/11/1981	
	A3	4,413,022	11/01/83	Suntola et al.	427	255.2	06/21/1979	
	A4	4,486,487	12/04/84	Skarp	428	216	04/25/1983	
	A5	4,767,494	08/30/88	Kobayashi et al.	156	606	09/19/1986	
	A6	4,806,321	02/21/89	Nishizawa et al.	422	245	07/21/1985	
	A7	4,829,022	05/09/89	Kobayashi et al.	437	107	12/09/1986	
	A8	4,834,831	05/30/89	Nishizawa et al.	156	611	09/04/1987	
	A9	4,838,983	06/13/89	Schumaker et al.	156	613	03/18/1988	
	A10	4,838,993	06/13/89	Aoki et al.	156	643	12/03/1987	
	A11	4,840,921	06/20/89	Matsumoto	437	89	06/30/1988	
	A12	4,845,049	07/04/89	Sunakawa	437	81	03/28/1988	
TMT	A13	4,859,625	08/22/89	Nishizawa et al.	437	81	11/20/1987	

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							YES	NO
TMT	B1	01/66832 A2	09/13/2001	WO	C30B	16/44		X
	B2	01/40541 A1	06/07/2001	WO	C23C	16/40		X
	B3	01/36702 A1	05/25/2001	WO	C23C	16/00		X
	B4	01/29893 A1	04/26/2001	WO	H01L	21/768		X
TMT	B5	01/29891 A1	04/26/2001	WO	H01L	21/768		X


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TMT	C1	Hultman, et al., "Review of the thermal and mechanical stability of TiN-based thin films", <i>Zeitschrift Fur Metallkunde</i> , 90(10) (Oct. 1999), pp. 803-813.
TMT	C2	Klaus, et al., "Atomic Layer Deposition of SiO ₂ Using Catalyzed and Uncatalyzed Self-Limiting Surface Reactions", <i>Surface Review & Letters</i> , 6(3&4) (1999), pp. 435-448.

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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

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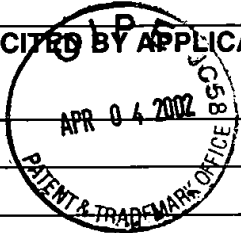
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*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
TMT	A14	4,859,627	08/22/89	Sunakawa	437	81	07/01/1988
	A15	4,861,417	08/29/89	Mochizuki et al.	156	610	03/24/1988
	A16	4,876,218	10/24/89	Pessa et al.	437	107	09/26/1988
	A17	4,927,670	05/22/1990	Erbil	427	255.3	06/22/1988
	A18	4,931,132	06/05/90	Aspnes et al.	156	601	10/07/1988
	A19	4,960,720	10/02/90	Shimbo	437	105	08/24/1987
	A20	4,975,252	12/04/90	Nishizawa et al.	422	245	05/26/1989
	A21	4,993,357	02/19/91	Scholz	118	715	12/21/1989
	A22	5,013,683	05/07/91	Petroff et al.	437	110	01/23/1989
	A23	5,082,798	01/21/92	Arimoto	437	108	09/27/1990
	A24	5,085,885	02/04/92	Foley et al.	477	38	09/10/1990
	A25	5,091,320	02/25/92	Aspnes et al.	437	8	06/15/1990
	A26	5,130,269	07/14/92	Kitahara et al.	437	111	04/25/1989
TMT	A27	5,166,092	11/24/92	Mochizuki et al.	437	105	10/30/1990

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							YES	NO
TMT	B6	01/29280 A1	04/26/2001	WO	C23C	16/32		X
	B7	01/27347 A1	04/19/2001	WO	C23C	16/44		X
	B8	01/27346 A1	04/19/2001	WO	C23C	16/44		X
TMT	B9	01/15220 A1	03/01/2001	WO	H01L	21/768		X

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TMT	C3	Yamaguchi, et al., "Atomic-layer chemical-vapor-deposition of silicon dioxide films with extremely low hydrogen content", <i>Appl. Surf. Sci.</i> , Vol. 130-132 (1998), pp. 202-207.
TMT	C4	George, et al., "Surface Chemistry for Atomic Layer Growth", <i>J. Phys. Chem.</i> , Vol. 100 (1996), pp. 13121-131.
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TMT	A28	5,225,366	07/06/93	Yoder	437	108	06/22/1990
	A29	5,246,536	09/21/93	Nishizawa et al.	156	610	03/10/1989
	A30	5,250,148	10/05/93	Nishizawa et al.	156	611	11/12/1991
	A31	5,254,207	10/19/93	Nishizawa et al.	156	601	11/30/1992
	A32	5,256,244	10/26/93	Ackerman	156	613	02/10/1992
	A33	5,270,247	12/14/93	Sakuma et al.	437	133	07/08/1992
	A34	5,278,435	01/11/94	Van Hove et al.	257	184	06/08/1992
	A35	5,281,274	01/25/94	Yoder	118	697	02/04/1993
	A36	5,290,748	03/01/94	Knuuttila et al.	502	228	07/16/1992
	A37	5,294,286	03/15/94	Nishizawa et al.	156	610	01/12/1993
	A38	5,296,403	03/22/94	Nishizawa et al.	437	133	10/23/1992
	A39	5,300,186	04/05/94	Kitahara et al.	156	613	04/07/1992
TMT	A40	5,311,055	05/10/94	Goodman et al.	257	593	11/22/1991


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	B11	00/79019 A1	12/28/2000	WO	C23C	16/00		X
TMT	B12	00/63957 A1	10/26/2000	WO	H01L	21/205		X

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TMT	C5	George, et al., "Atomic layer controlled deposition of SiO ₂ and Al ₂ O ₃ using ABAB...binary reaction sequence chemistry", <i>Appl. Surf. Sci.</i> , Vol. 82/83 (1994), pp. 460-467.
TMT	C6	Wise, et al., "Diethyldiethoxysilane as a new precursor for SiO ₂ growth on silicon", <i>Mat. Res. Soc. Symp. Proc.</i> , Vol. 334 (1994), pp. 37-43.

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JMT	A41	5,316,615	05/31/94	Copel	117	95	03/09/1993
	A42	5,316,793	05/31/94	Wallace et al.	427	248.1	07/27/1992
	A43	5,330,610	07/19/94	Eres et al.	117	86	05/28/1993
	A44	5,336,324	08/09/94	Stall et al.	118	719	12/04/1991
	A45	5,338,389	08/16/94	Nishizawa et al.	117	89	04/21/1993
	A46	5,348,911	09/20/94	Jurgensen et al.	117	91	04/26/1993
	A47	5,374,570	12/20/94	Nasu et al.	437	40	08/19/1993
	A48	5,395,791	03/07/95	Cheng et al.	437	105	10/20/1993
	A49	5,438,952	08/08/1995	Otsuka	117	84	01/31/1994
	A50	5,439,876	08/08/95	Graf et al.	505	447	08/16/1993
	A51	5,441,703	08/15/95	Jurgensen	422	129	03/29/1994
	A52	5,443,033	08/22/95	Nishizawa et al.	117	86	03/11/1994
	A53	5,443,647	08/22/95	Aucoin et al.	118	723 ME	07/11/1994
JMT	A54	5,455,072	10/03/95	Bension et al.	427	255.7	11/18/1992

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							YES	NO
JMT	B13	00/54320 A1	09/14/2000	WO	H01L	21/44		X
	B14	00/16377 A2	03/23/2000	WO	H01L	---		X
	B15	00/15881 A2	03/23/2000	WO	C30B	---		X
JMT	B16	00/15865 A1	03/23/2000	WO	C23C	16/00		X

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JMT	C7	Niinisto, et al., "Synthesis of oxide thin films and overlayers by atomic layer epitaxy for advanced applications", <i>Mat. Sci. & Eng.</i> , Vol. B41 (1996), pp. 23-29.

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TMT	A55	5,458,084	10/17/95	Thorne et al.	117	89	12/09/1993
	A56	5,469,806	11/28/95	Mochizuki et al.	117	97	08/20/1993
	A57	5,480,818	01/02/96	Matsumoto et al.	437	40	02/09/1993
	A58	5,483,919	01/16/96	Yokoyama et al.	117	89	08/17/1994
	A59	5,484,664	01/16/96	Kitahara et al.	428	641	01/21/1994
	A60	5,503,875	04/02/96	Imai et al.	427	255.3	03/17/1994
	A61	5,521,126	05/28/96	Okamura et al.	437	235	06/22/1994
	A62	5,527,733	06/18/96	Nishizawa et al.	437	160	02/18/1994
	A63	5,532,511	07/02/96	Nishizawa et al.	257	627	03/23/1995
	A64	5,540,783	07/30/96	Eres et al.	118	725	05/26/1994
	A65	5,601,651	02/11/97	Watabe	118	715	12/14/1994
	A66	5,616,181	04/01/97	Yamamoto et al.	118	723 ER	11/21/1995
TMT	A67	5,637,530	06/10/97	Gaines et al.	114	105	06/10/1996

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	B18	99/29924 A1	06/17/1999	WO	C23C	16/04		X
	B19	99/01595	01/14/1999	WO	C30B	25/14		X
TMT	B20	96/18756 A1	06/20/1996	WO	C23C	16/08		X

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TMT	C8	Klaus, et al., "Atomically controlled growth of tungsten and tungsten nitride using sequential surface reactions". <i>Appl. Surf. Sci.</i> , Vol 162-163 (2000), pp. 479-491.
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TMT	A68	5,641,984	06/24/97	Aftergut et al.	257	433	08/19/1994	
	A69	5,644,128	07/01/97	Wollnik et al.	250	251	08/25/1994	
	A70	5,693,139	12/02/97	Nishizawa et al.	117	89	06/15/1993	
	A71	5,705,224	01/06/98	Murota et al.	427	248.1	01/31/1995	
	A72	5,707,880	01/13/98	Aftergut et al.	437	3	01/17/1997	
	A73	5,711,811	01/27/98	Suntola et al.	118	711	11/28/1995	
	A74	5,730,802	03/24/98	Ishizumi et al.	118	719	12/27/1996	
	A75	5,747,113	05/05/98	Tsai	427	255.5	07/29/1996	
	A76	5,749,974	05/12/98	Habuka et al.	118	725	07/13/1995	
	A77	5,796,116	08/18/98	Nakata et al.	257	66	07/25/1995	
	A78	5,807,792	09/15/98	Ilg et al.	438	758	12/18/1996	
	A79	5,830,270	11/03/98	McKee et al.	117	106	08/05/1996	
TMT	A80	5,835,677	11/10/98	Li et al.	392	401	10/03/1996	

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							YES	NO
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	B22	93/02111 A1	02/04/1993	WO	C08F	4/78		X
	B23	91/10510 A1	07/25/1991	WO	B01J	37/02		X
TMT	B24	0 799 641 A2	10/08/1997	EP	B01J	20/32		X

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TMT	C09	Min, et al., "Atomic layer deposition of TiN thin films by sequential introduction of Ti precursor and NH/sub3", <i>Symp.: Advanced Interconnects and Contact Materials and Processes for Future Integrated Circuits</i> (Apr. 13-16, 1998), pp. 337-342.

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TMT	A81	5,851,849	12/22/98	Comizzoli et al.	438	38	05/22/1997	
	A82	5,855,675	01/05/99	Doering et al.	118	719	03/03/1997	
	A83	5,855,680	01/05/99	Soininen et al.	118	719	11/28/1995	
	A84	5,858,102	01/12/99	Tsai	118	719	02/14/1998	
	A85	5,904,565	05/18/1999	Nguyen, et al.	438	687	07/17/1997	
	A86	5,923,056	07/13/99	Lee et al.	257	192	03/12/1998	
	A87	5,923,985	07/13/99	Aoki et al.	438	301	01/14/1997	
	A88	5,925,574	07/20/99	Aoki et al.	437	31	04/10/1992	
	A89	5,942,040	08/24/99	Kim et al.	118	726	08/27/1997	
	A90	5,947,710	09/07/1999	Cooper, et al.	418	63	06/16/1997	
	A91	6,001,669	12/14/99	Gaines et al.	438	102	07/21/1992	
	A92	6,015,590	01/18/00	Suntola et al.	427	255.23	11/28/1995	
TMT	A93	6,025,627	02/15/00	Forbes et al.	257	321	05/29/1998	

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I	B26	0 344 352 A1	12/06/1989	EP	H01L	39/24		X
TMT	B27	62-091495 A	04/25/1987	JP	C30B	25/02		X

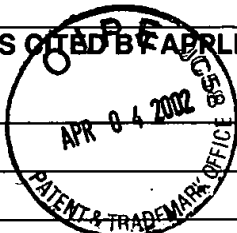
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TMT	C11	Min, et al., "Metal-Organic Atomic-Layer Deposition of Titanium-Silicon-Nitride Films", Applied Physics Letters, American Inst. Of Physics, Vol 75(11) (Sept. 13, 1999).

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	A95	6,042,652	03/28/00	Hyun et al.	118	719	09/07/1999
	A96	6,043,177	03/28/00	Falconer et al.	502	4	01/21/1997
	A97	6,124,158	09/26/00	Dautartas et al.	438	216	06/08/1999
	A98	6,113,977	09/05/00	Soininen et al.	427	64	09/11/1997
	A99	6,130,147	10/10/00	Major et al.	438	604	03/18/1997
	A100	6,139,700	10/31/00	Kang et al.	204	192.17	09/30/1998
	A101	6,174,377	01/16/2001	Doering, et al.	118	729	01/04/1999
	A102	6,174,809	01/16/2001	Kang, et al.	438	682	12/15/1998
	A103	6,200,893	03/13/2001	Sneh	438	685	03/11/1998
	A104	6,203,613	03/20/2001	Gates, et al.	117	104	10/19/1999
TMT	A105	6,207,302	03/27/2001	Sugiura, et al.	428	690	03/02/1998

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	B29	03-048421	03/01/1991	JP	H01L	21/302		X
	B30	03-286531	12/17/1991	JP	H01L	21/316		X

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TMT	C12	Martensson, et al., "Atomic Layer Epitaxy of Copper on Tantalum", <i>Chemical Vapor Deposition</i> , 3(1) (Feb. 1, 1997), pp. 45-50.
TMT	C13	Ritala, et al. "Atomic Layer Epitaxy Growth of TiN Thin Films", <i>J. Electrochem. Soc.</i> , 142(8) (Aug. 1995), pp. 2731-737.
TMT	C14	Elers, et al., "NbC15 as a precursor in atomic layer epitaxy", <i>Appl. Surf. Sci.</i> , Vol. 82/83 (1994), pp. 468-474.

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Examiner Unknown								

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*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate	
TMT	A106	6,248,605	06/19/2001	Harkonen, et al.	438	29	06/02/1999	
	A107	6,270,572	08/07/2001	Kim, et al.	117	93	08/09/1999	
	A108	6,287,965	09/11/2001	Kang, et al.	438	648	02/23/2000	
	A109	6,291,876	09/18/2001	Stumborg, et al.	257	632	08/20/1998	
	A110	6,305,314	10/23/2001	Sneh, et al.	118	723 R	12/17/1999	
	A111	6,306,216	10/23/2001	Kim, et al.	118	725	07/12/2000	
	A112	6,316,098	11/13/2001	Yitzchaik, et al.	428	339	03/23/1999	
	A113	2001/0000866	05/10/2001	Sneh, et al.	118	723 R	11/29/2000	
	A114	2001/0009140	07/26/2001	Bondestam, et al.	118	725	01/25/2001	
	A115	2001/0011526	08/09/2001	Doering, et al.	118	729	01/16/2001	
TMT	A116	2001/0031562	10/18/2001	Raaijmakers, et al.	438	770	02/22/2001	

Foreign Patent Documents

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TMT	B31	04-031396 A	02/03/1992	JP	C30B	25/14		X
	B32	06-291048	10/18/1994	JP	H01L	21/205		X
	B33	08-264530	10/11/1996	JP	H01L	21/3205		X
TMT	B34	11-269652	10/05/1999	JP	C23C	16/44		X

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*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.
TMT	C15	Lee, "The Preparation of Titanium-Based Thin Film by CVD Using Titanium Chlorides as Precursors", <i>Chemical Vapor Deposition</i> , 5(2) (Mar. 1999), pp. 69-73.
TMT	C16	Martensson, et al., "Atomic Layer Epitaxy of Copper, Growth & Selectivity in the Cu (II)-2,2,6,6-Tetramethyl-3, 5-Heptanedion ATE/H2 Process", <i>J. Electrochem. Soc.</i> , 145(8) (Aug. 1998), pp. 2926-2931.

Examiner	T. M. Thomas	Date Considered	01-16-03
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U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)					Docket No. AMAT/5192		Serial No. 09/776,329	
LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT (Use several sheets if necessary)					Applicant Seutter, et al.		Confirmation No. 9575	
					Filing Date February 02, 2001		Group 2812	
		Examiner Unknown						

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TMT	A117	2001/0034123	10/25/2001	Jeon, et al.	438	643	04/06/2001
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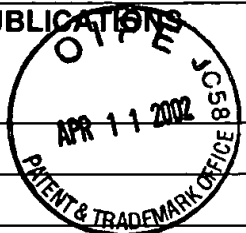
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	B37	100 27 047	01/09/1997	DE	H01L	21/283		X
	B38	2 626 110	07/21/1989	FR	H01L	39/24		X
	B39	2 692 597	12/24/1993	FR	C23C	16/00		X
TMT	B40	2 355 727A	05/02/2001	GB	C23C	16/44		X

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*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.
TMT	C17	Min, et al., "Chemical Vapor Deposition of Ti-Si-N Films with Alternating Source Supply", <i>Mat., Res. Soc. Symp. Proc.</i> , Vol. 564 (Apr. 5, 1999), pp. 207-210
TMT	C18	Bedair, "Atomic layer epitaxy deposition processes", <i>J. Vac. Sci. Technol.</i> 12(1) (Jan/Feb 1994)
TMT	C19	Yamaga, et al., "Atomic layer epitaxy of ZnS by a new gas supplying system in a low-pressure metalorganic vapor phase epitaxy", <i>J. of Crystal Growth</i> 117 (1992), pp. 152-155
TMT	C20	Elam, et al., "Nucleation and growth during tungsten atomic layer deposition on SiO ₂ surfaces," <i>Thin Solid Films</i> 386 (2001) Pages 41 - 52, (Accepted Dec. 14, 2000).
Examiner T. M. Thomas		Date Considered 01-16-03

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U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)		Docket No. APPM/5192	Serial No. 09/776,329
SUPPLEMENTAL LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT		Applicant Seutter, et al.	Confirmation No.: 9575
(Use several sheets if necessary)		Filing Date February 2, 2001	Group 2812
Examiner Unknown			



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	A2	4,917,556	04/17/90	Stark et al.	414	217	05/26/89
	A3	4,951,601	08/28/90	Maydan, et al.	118	719	06/23/89
	A4	5,000,113	03/19/91	Wang et al.	118	723	12/19/86
	A5	5,028,565	07/02/91	Chang, et al.	437	192	08/25/89
	A6	5,173,474	12/22/92	Connell, et al.	505	1	03/11/91
	A7	5,186,718	02/16/93	Tepman et al.	29	25.01	04/15/91
	A8	5,205,077	04/27/93	Wittstock	51	165 R	08/28/91
	A9	5,234,561	08/10/93	Randhawa et al.	204	192.38	08/25/88
	A10	5,259,881	11/09/93	Edwards, et al.	118	719	05/17/91
	A11	5,286,296	02/15/94	Sato et al.	118	719	01/09/92
	A12	5,580,380	12/03/96	Liu et al.	117	86	01/30/95
	A13	5,609,689	03/11/97	Kato et al.	118	719	06/03/96
	A14	5,667,592	09/16/97	Boitnott et al.	118	719	04/16/96
	A15	5,674,786	10/07/97	Turner et al.	437	225	06/05/95
	A16	5,695,564	12/09/97	Imahashi	118	719	08/03/95
	A17	5,730,801	03/24/98	Tepman et al.	118	719	08/23/94
	A18	5,788,447	08/04/98	Yonemitsu et al.	414	217	08/05/96
	A19	5,788,799	08/04/98	Steger, et al.	156	345	06/11/96
	A20	5,801,634	09/01/98	Young et al.	340	635	09/08/97
	A21	5,856,219	01/05/99	Naito et al.	438	241	08/18/97
	A22	5,866,213	02/02/99	Foster et al.	427	573	07/19/97
	A23	5,866,795	02/02/99	Wang et al.	73	1.36	03/17/97
	A24	5,882,165	03/16/99	Maydan et al.	414	217	09/10/97
	A25	5,882,413	03/16/99	Beaulieu et al.	118	719	07/11/97
TMT	A26	5,928,389	07/27/99	Jevtic	29	25.01	10/21/96

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		Seutter, et al.	9575
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Examiner Unknown		February 2, 2001	2812

**Foreign Patent Documents**

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Examiner <u>T. M. Thomas</u>	Date Considered <u>01-26-03</u>
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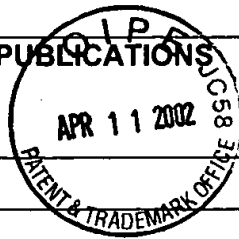
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U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)		Docket No. APPM/5192	Serial No. 09/776,329
SUPPLEMENTAL LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT		Applicant Seutter, et al.	Confirmation No.: 9575
(Use several sheets if necessary)		Filing Date February 2, 2001	Group 2812
Examiner Unknown			



Foreign Patent Documents

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
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TMT	B97	05-175143	07/13/1993	JP	H01L	21/205	<input checked="" type="checkbox"/>	<input type="checkbox"/>
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Examiner T. M. Thomas Date Considered 01-26-03

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TMT	B146	2001-220294	08/14/2001	JP	C30B	29/20	<input checked="" type="checkbox"/>	<input type="checkbox"/>


Examiner V. M. Thomas Date Considered 01-26-03

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U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)		Docket No. APPM/5192	Serial No. 09/776,329
SUPPLEMENTAL LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT		Applicant Seutter, et al.	Confirmation No.: 9575
(Use several sheets if necessary)		Filing Date February 2, 2001	Group 2812
Examiner Unknown			
OTHER ART			
*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.	
TMT	C1	Ohba, et al., "Thermal Decomposition of Methylhydrazine and Deposition Properties of CVD TiN Thin Films", Conference Proceedings, Advanced Metallization for ULSI Applications in 1993 (1994), pp. 143-149 ✓	
	C2	Scheper, et al., "Low-temperature deposition of titanium nitride films from dialkylhydrazine-based precursors", Materials Science in Semiconductor Processing 2 (1999), pp. 149-157 ✓	
	C3	Suzuki, et al., "A 0.2-μm contact filing by 450°C-hydrazine-reduced TiN film with low resistivity", IEDM 92-979, pp. 11.8.1 – 11.8.3 ✓	
	C4	Suzuki, et al., "LPCVD-TiN Using Hydrazine and TiCl ₄ ", VMIC Conference (June 8-9, 1993), pp. 418-423	
	C5	IBM Tech. Disc. Bull. "Knowledge-Based Dynamic Scheduler in Distributed Computer Control, (June 1990), pp. 80-84	
	C6	IBM Tech. Disc. Bull. "Multiprocessor and Multitasking Architecture for Tool Control of the Advanced via Inspection Tools" (May 1992), pp. 190-191	
	C7	McGeachin, S., "Synthesis and properties of some β-diketimines derived from acetylacetone, and their metal complexes", Canadian J. of Chemistry, Vol. 46 (1968), pp.1903-1912	
	C8	Solanki, et al., "Atomic Layer deposition of Copper Seed Layers", Electrochemical and Solid State Letters, 3(10) (2000), pp. 479-480	
	C9	NERAC.COM Retro Search: Atomic Layer Deposition of Copper, dated October 11, 2001	
	C10	NERAC.COM Retro Search: Atomic Layer Deposition / Epitaxy Aluminum Oxide Plasma, dated October 2, 2001	
	C11	NERAC Search abstract of "Atomic Layer deposition of Ta and Ti for Interconnect Diffusion Barriers", by Rossnagel, et al., J. Vac. Sci. & Tech., 18(4) (July 2000)	
	C12	Abstracts of articles re atomic layer deposition	
	C13	Abstracts of search results re atomic layer deposition, search dated January 24, 2002	
	C14	Abstracts of articles re atomic layer deposition and atomic layer nucleation	
TMT	C15	Abstracts of articles re atomic layer deposition and semiconductors and copper	
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SUPPLEMENTAL LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT		Applicant Seutter, et al.	Confirmation No.: 9575
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OTHER ART		
*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.
TMT	C16	Abstracts of articles – atomic layer deposition
	C17	NERAC Search – Atomic Layer Deposition, search dated October 16, 2001
	C18	Bader, et al., "Integrated Processing Equipment", Solid State Technology, Cowan Pub., Vol. 33, No. 5 (May 1, 1990), pp. 149-154
	C19	Choi, et al., "The effect of annealing on resistivity of low pressure chemical vapor deposited titanium diboride", J. Appl. Phys. 69(11) (June 1, 1991), pp. 7853-7861
	C20	Choi, et al., "Stability of TiB ₂ as a Diffusion Barrier on Silicon", J. Electrochem. Soc. 138(10) (October 1991), pp. 3062-3067
	C21	"Cluster Tools for Fabrication of Advanced devices" Jap. J. of Applied Physics, Extended Abstracts, 22 nd Conference Solid State Devices and Materials (1990), pp. 849 – 852 XP000178141 (ARTICLE ON ORDER – TO BE PROVIDED)
	C22	"Applications of Integrated processing", Solid State Technology, US, Cowan Pub., Vol 37, No. 12 (December 1, 1994), pp. 45-47
	C23	Kitigawa, et al., "Hydrogen-mediated low temperature epitaxy of Si in plasma-enhanced chemical vapor deposition", Applied Surface Science (2000), pp. 30-34 (ARTICLE ON ORDER – TO BE PROVIDED)
TMT	C24	Lee, et al., "Pulsed nucleation for ultra-high aspect ratio tungsten plugfill", Novellus Systems, Inc. (2001), pp. 1-2 (ARTICLE ON ORDER – TO BE PROVIDED)
Examiner	T. M. Thomas	
Date Considered	01-26-03	

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT #5		Applicant Suetter, et al.	Confirmation No.: 9575
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U.S. Patent Documents

*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
TMT	A1	2001/0042799	11/22/2001	Kim, et al.	239	553	February 2, 2001

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OTHER ART

*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.
		* Already Cited (Duplicates)
	C1	"Cluster Tools for Fabrication of Advanced devices" Jap. J. of Applied Physics. Extended Abstracts, 22 nd Conference Solid State Devices and Materials (1990), pp. 849 - 852
	C2	Kitigawa, et al., "Hydrogen-mediated low temperature epitaxy of Si in plasma-enhanced chemical vapor deposition", Applied Surface Science (2000), pp. 30-34
	C3	Lee, et al., "Pulsed nucleation for ultra-high aspect ratio tungsten plugfill", Novellus Systems, Inc. (2001), pp. 1-2 (COPY NOT AVAILABLE TO APPLICANT AT THIS TIME)

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